



Sheet 1 of 1

Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. <b>30848/40323</b>	Serial No. <b>10/502,465</b>
<b>INFORMATION DISCLOSURE STATEMENT</b>		Applicant <b>Androula G. Nassiopoulou</b>	
		Filing Date <b>1/16/03</b>	Group <b>2878</b>

U.S. PATENT DOCUMENTS							
*Examiner Initials	Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate	
<i>FAR</i>	6,359,276 B1	03/19/02	Tu	250	338.1	07/06/99	

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*Examiner Initials	Document Number	Publication Date	Country	Class	Subclass	Translation	
						Yes	No
<i>FAR</i>	1,251,945	05/03/00	China			Abstract only	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
<i>FAR</i>	"Porous Silicon Bulk Micromachining for Thermally Isolated Membrane Formation", Dücsö et al., Sensors and Actuators, A 60, 1997, pp. 235-239
<i>FAR</i>	"Micromachined Silicon Thermopile and Thermal Radiators Using Porous Silicon Technology", Dobrzański et al., IEE Proc.-Optoelectron, Vol. 145, No. 5, October 1998, pp. 307-311
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<i>FAR</i>	"Multi-Walled Microchannels: Free-Standing Porous Silicon Membranes for Use in $\mu$ TAS", Tjerkstra et al., Journal of Microelectromechanical Systems, Vol. 9, No. 4, December 2000, pp. 495-501
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Examiner <i>Rudolf F. Rosenberger, E</i>	Date Considered <i>5/3/2005</i>
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